



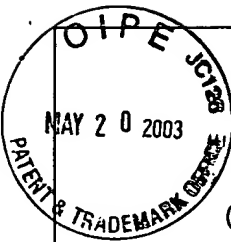
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INFORMATION DISCLOSURE STATEMENT BY APPLICANT Form PTO-1449 (Modified) (Use several sheets if necessary)				COMPLETE IF KNOWN	
				Application Number	09/888,002
				Confirmation Number	9049
				Filing Date	June 21, 2001
				First Named Inventor	Whonchee Lee
				Group Art Unit	3723
				Examiner Name	Dung V. Nguyen
Sheet	1	of	5	Attorney Docket No.	108298515US3

U.S. PATENT DOCUMENTS						
Examiner Initials*	Cite No.	U.S. Patent or Application		Name of Patentee or Inventor of Cited Document	Date of Publication or Filing Date of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		NUMBER	Kind Code (if known)			
DVN		U.S. Application No. 09/651,779 ✓ (Atty. Docket No. 10829.8515US)		Moore	Filed 08/30/2000	
		U.S. Application No. 09/651,808 ✓ (Atty. Docket No. 4373US)		Chopra et al.	Filed 08/30/2000	
		U.S. Application No. 09/653,392 ✓ (Atty. Docket No. MTI-31044)		Chopra et al.	Filed 08/31/2000	
		U.S. Application No. 10/090,869 ✓ (Atty. Docket No. 10829.8544US)		Moore et al.	Filed 03/04/2002	
		U.S. Application No. 10/230,463 ✓ (Atty. Docket No. 10829.8672US)		Lee et al.	Filed 08/29/2002	
		U.S. Application No. 10/230,602 ✓ (Atty. Docket No. 10829.8674US)		Chopra	Filed 08/29/2002	RECEIVED MAY 28 2003 TECHNOLOGY CENTER R3700
		U.S. Application No. 10/230,628 ✓ (Atty. Docket No. 10829.8673US)		Lee et al.	Filed 08/29/2002	
		U.S. Application No. 10/230,970 ✓ (Atty. Docket No. 10829.8515US6)		Lee et al.	Filed 08/29/2002	
		U.S. Application No. 10/230,972 ✓ (Atty. Docket No. 10829.8515US7)		Lee et al.	Filed 08/29/2002	
		U.S. Application No. 10/230,973 ✓ (Atty. Docket No. 10829.8515US8)		Lee et al.	Filed 08/29/2002	
		20020025759 ✓ (Atty. Docket No. 10829.8515US2)	A1	Lee et al.	02/28/2002	
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		2001/0036746 ✓	A1	Sato et al.	11/01/2001	
		2002/0052126 ✓	A1	Lee et al.	05/02/2002	

EXAMINER <i>Dung van Nguyen</i>	DATE CONSIDERED 6-13-2003
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DVN		2002/0070126 ✓	A1	Sato et al.	06/13/2002	
		4,839,005 ✓		Katsumoto et al.	06/13/1989	
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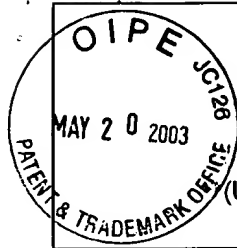
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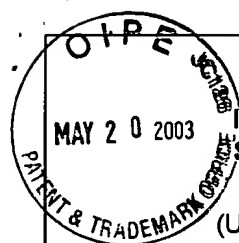
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Sheet 4 of 5

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		Office	NUMBER	Kind Code (if known)				
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		WO	00/59008	A2, A3	Nutool, Inc.	10/05/2000		
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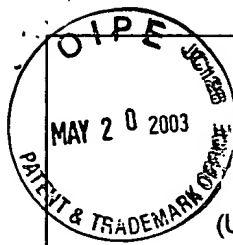
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume issue number(s), publisher, city and/or country where published.	T
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Sheet 5 of 5

OTHER PRIOR ART-NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume issue number(s), publisher, city and/or country where published.	T
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#12

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DVN	AA	U.S. Application No. 10/090,869 (Atty. Docket No. 10829.8544US)		Moore et al.	Filed 03/04/2002	

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